

Substitute for form 1449A/PTO (modified)

# INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Page 1 of 2

Application Number	---
Filing Date	November 20, 2003
First Named Inventor	Theiss, Steven D
Art Unit	---
Examiner Name	---
Attorney Case Number	57389US004

## U.S. Patent Documents

Exam. Init.*	Cite No.	Document Number	Publication Date or Issue Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	(This field is not required Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear)
		Doc. Number-(Kind Code if Known) (Add Kind Code after patent No. when available)			
SQG	A1	US- 2002/0195929 A1	12/26/2002	Haase et al.	
SQG	A2	US- 2003/0100779 A1	05/29/2003	Vogel et al.	
SQG	A3	US- 2003/0105365 A1	06/05/2003	Smith et al.	
SQG	A4	US- 2003/0150384 A1	08/14/2003	Baude et al.	
SQG	A5	US- 2003/0151118 A1	08/14/2003	Baude et al.	
SQG	A6	US- 2003/0152691 A1	08/14/2003	Baude et al.	
SQG	A7	US- 5,238,861	08/24/1993	Morin et al.	
SQG	A8	US- 5,264,383	11/23/1993	Young	
SQG	A9	US- 5,294,869	03/15/1994	Tang et al.	
SQG	A10	US- 5,294,870	03/15/1994	Tang et al.	
SQG	A11	US- 5,501,893	03/26/1996	Laermer et al.	
SQG	A12	US- 5,625,199	04/29/1997	Baumbach et al.	
SQG	A13	US- 6,037,712	03/14/2000	Codama et al.	
SQG	A14	US- 6,091,196	07/18/2000	Codama	
SQG	A15	US- 6,413,790 B1	07/02/2002	Duthaler et al.	
SQG	A16	US- 6,417,034 B2	07/09/2002	Kitazume et al.	

## Foreign Patent Documents

Exam. Init.*	Cite No.	Foreign Patent Document		Publication Date MM-DD-YYYY	(This field is not required)Name of Patentee or Applicant of Cited Document	(This field is not required Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear)	Translation (Check if yes)
		Ctry. Code	Number-KindCode (if known)				
SQG	B1	EP	0 762 806 A2	03/12/1997			
SQG	B2	EP	1 003 221 A2	05/24/2000			
SQG	B3	JP	2000-132762	05/12/2000			X
SQG	B4	WO	00/10196	02/24/2000			
	B5						
	B6						
	B7						

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## OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

Exam. Init.*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published
SOG	C1	S. M. SZE, Physics of Semiconductor Devices, (1981), pp. 438-442, 492-493, 2 <sup>nd</sup> Edition, John Wiley & Sons, New York
SOG	C2	C. D. DIMITRAKOPoulos et al., "Organic Thin-Film Transistors: A Review of Recent Advances", IBM J. Res. & Dev., (January 2001), pp.11-27, Vol. 45, No. 1
SOG	C3	L. C. SANDER et al., "Polycyclic Aromatic Hydrocarbon Structure Index", NIST Special Publication 922 (December 1997)
SOG	C4	H. KLAUK et al., "Pentacene Organic Thin-Film Transistors and ICs", Solid State Technology, (March 2000), pp.63-76, Vol. 43, No. 3
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SOG	C7	P. F. TIAN et al., "Precise, Scalable Shadow Mask Patterning, of Vacuum-Deposited Organic Light Emitting Devices", Journal of Vacuum Science & Technology A; Vacuum, Surfaces, and Films, (Sept/Oct 1999), 2 <sup>nd</sup> Series, Vol. 17, No. 5
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SOG	C10	S. SHERR, "Matrix and Alphanumeric Devices", Electronic Displays, (1993), pp. 201-340, John Wiley and Sons, New York
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SOG	C14	M. MADOU Fundamentals of Microfabrication, (1997), pp. 166-179, CRC Press LLC

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5/29/04

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